**JEOL Scanning electron microscope JSM-5410LV,** Ulvac pump brand, Eyela cooling circulator, Oxford EDS, JEOL SemAfore Software, Software for control and evaluation License, Sputter coater.



manufacturer: JEOL (SEM) model: JSM - 5410LV

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#### DESCRIPTION, SPECIFICATIONS AND INSTALLATION REQUIREMENTS

The JSM-5410LV Scanning Microscope can be used for observation of the entire Area of large sized specimens up to 5-inch in diameter by rotating them. The whole series of operation including vacuum evacuation, image observation, focusing, and photographing have been automated. Moreover, provision of digitally processed still image allows very easy observation of images even in a bright room, making the JSM-5410LV outstanding in operability.

Another feature of the JSM-5410LV is that an energy dispersive X-ray spectro-meter (EDS) and a wavelength dispereive X-ray spectrometer (WDS) can he attached to the apecimen chamber at the same time. The JSM-5410LV+EDS a-high performance multipurpose scanning electron microscope capable of extending its utility from morphological observation to elemental analysis.

#### **JEOL SEM 5410LV SPECIFICATIONS**

Performance	
Resolution :	3.5 nm (at 30 kV, WD = 8 mm),
	SEI (secondary electron image) mode
Magnification:	x15 (WD = 48 um) to 200,000 (25 steps)
-	Digital indication
Image modes:	Secondary electron image (SEI) HV Mode
	Backscattered electron image (BEI) HV Mode
	Backscattered electron image (BEI) LV Mode

# EOS (electron optical system)

Accelerating voltage	
(Acc.V.):	0.5 to 30 kV
	0.5 to 3 kV, 0.1 kV/step (26 steps)
	5 to 30 kV, 5 kV/step (6 steps)
	Hysteresis elimination function is linked for Acc V change
Electron dun filament:	Precentered W/ hairpin filament (K-Type)
Electron gun marient.	Hingo tupo gun onon/close mechanism
	Hinge type gun open/ciose mechanism
Fliament monitor	Bulit-In
Gun bias	
AUTO mode:	Automatic selection of the following 2 ranges:
	For high Acc.V. (2.1 to 30 kV)
	For low Acc.V. (0.3 to 2 kV)
MAN mode:	Continuously variable manually
Alianment <sup>.</sup>	Electromagnetic deflection type
l ens system:	3-stane
Lono oyotom.	Zoom condenser lens (CL): 2-stage
	Objective lens (OL): single stege
	Variable time (OL). Single-Stage
OL aperture	variable type (3-step)
	Fine position adjustable
Focus wobbler:	Built-in (usable in TV mode)
Focusing:	Push-Button and knob type
	Manual, and automatic focusing device (AFD) built-in
	Automatic focus tracer (AFT) buflt-in.
Stigmator:	8-pole electromagnetic type
-	Manual, and automatic astigmatism correction device (ASD)
	built-in
	Stigmator memory built-in
Specimen tilt	0 to approx 90° correctable
correction:	Dynamic Eccusing Dovice(DELI) built-in
Seepping coil:	2 store electromagnetic deflection type
	z-stage electromagnetic dellection type
Magnification control:	Automatic magnification corrector (MAC) built-in
Viewing field fine	
shift:	Electromagnetic type
	±10µm (at 30 kV, WD 20 mm) in all directions by JOYSTICK
	control
Probe current range : 10 <sup>-12</sup>	to 10 <sup>-6</sup> A
Specimen Stage	
Type	Eucentric aoniometer
Specimen movements	
X direction shift:	80 mm
V direction shift:	40 mm
Till.	$-10.00 + 90^{-1}$
Rotation	360° (endless).
Working distance (WD):	8 to 48 mm continuously variable
	Digital indication an LCD by Z sensor
Working distance (EDS):	20 mm. ±1mm.variable
Specimen size:	10 mm dia. x 5 mmh, 10 mm dia. x 10 mmh
	32 mm dia. x 5 mmh, 32 mm dia. x 10 mmh
	51 mm dia. x 5 mmh, 51 mm dia. x 10 mmh
	72 mm dia. x 5 mmh, 76 mm dia. X10 mmh

Specimen exchange:	Draw-out type Slide type mechanism for loading/unloading of specimens			
Detectors SE/BE detector	Consists of a collector, scintillator, light Guide and a photomultiplier tube			
Scanning System Scanning modes:	PIC (frame scan) TV (frame scan) LSP (line scan)			
Scanning speed For observation:	0.27, 0.58, 2.88, 9.6 s/frame, TV scan (TV scap for SEL only)			
For photographing:	50 Hz: > on LCD 28.8 s/frame >> on LCD 86.4 s/frame 60 Hz: > on LCD 24 s/frame >> on LCD 72 s/frame			
<b>Display System</b> Magnification display:	x15 to 200,000 (On LCD, and CRT in PIC1 mode only)			
Observation CRT: Frame size: Image quality control Manual control: Auto control:	2 , 9-inch CRT 135 x 18G mm (TV mode) Rapid exposure system (display on CRT) Automatic contrast and brightness control			
Observation condition displa	(ACB) built-in av			
Upper line on LCD :	Accelerating voltage Magnification Working distance Film number ACB linkage indication (A; ON/OFF)			
Lower line on LCD :	Evacuation sequence Warning/Photo monitor/Check data			
Observation CRT:	Digital display in the PIC1 mode only Accelerating voltage Magnification (ON/OFF) Micron marker with value Film number			
Photo Recording System				
Exposure meter: Shutter: Photo monitor Data recording Data display: Image on character Base: Data contents:	Rapid exposure system (displayed on CRT) Automatic shutter built-in Digital indication on LCD			
	ON/OFF selectable (on CRT and Photograph)			
	ON/OFF selectable Accelerating voltage Magnification Micron marker with value Film number (4-digit: manual set, and 2-digit: manual/auto set)			

Data display modes	All data ON Magnification OFF Micron marker (with value) ON only			
Camara for scanning				
image(option):	Manual and automatic shutters built-In			
MP-35040:	For instant pack film (0.75)			
Recording CRT:	One, 9-inch CRT			
Image Frame Store System Memory capacity	n			
Number of pixels:	512 x 512 (512 x 480 for image)			
Number of grav	······································			
Scale steps:	256			
Number of frames	One (Video graphic printer with 4-frame expand			
	functions optionally available)			
Still image display				
CRT	One, 9-ineh CRT (EIA, interlace scan type)			
Frame size:	Approx. 128 x 166 mm			
Vacuum System				
Control:	Fully automatic sequence control •			
	(electro magnetic valves used)			
	Evacuation sequence is indicated on LCD			
Ultimate pressure:	Approx. 7 x $10^{4}$ Pa (5 x $10^{-6}$ Torr)			
Evaeuation time:	Approx. 2.5 min			
Vacuum pumps:	One, 420 lit./s oil diffusion pump with water cooling baffle			
	One, 100 lit./min oil rotary pump (RP)			
Vacuum gauge	One, Pirani gauge			
	Pressure is indicated as a % on LCD.			
Checkers and Safety Device Checkers	es •			
Auto checkers:	5 warning indication on LCD			
Manual checkers:	8-item indication on LCD (including 2 items			
	For optional devices)			
Safety devices:	Protective devices are built-in for power and			
	Water failures, and pressure increase.			
Others				
Ports for X-ray				
Measurement:	for optional for EDS (energy dispersive X-ray spectrometer)			
I V output terminals :	I wo BNC-R connectors (75 onms)			
TV output signal:	(FOF IV mode and suil image)			
i v output signal.	Still image: EIA			
	Sull Illage, EIA Composito, positivo polarity			
	1  Vn-n H = 15.75  kHz  V = 60  Hz			
Service outlet:	One, 100 V AC, 2 A			
Installation Requirements	A/-1			
Power Supply and Cooling				
Power supply:	Single-phase 220 V( $\pm 10\%$ ) AC, 50/60 HZ, 5 KVA			
Grounding torminal	(voltage drop at 5 kv A should be within 3%). One 100 ebms or less			
Cooling water				
Faucet:	One. 10 to 12 mm O.D.			
Drain:	One. 25 mm I.D. or more			
	· · · ·			

Flow rate:	2 lit./min.
Pressure:	0.05 to 0.2 kPa.
Temperature:	20±5°C.
-	(At SEM's water outlet should be 35°C or less.)

### Environment

Temperature:	20±5°C.
Humidity	60% or less.
Stray magnetic field :	0.3µT or less.
Floor vibration:	2 µm or less at 5 Hz (in X, Y and Z directions).
Floor space:	2,500(W) x 2,300(D) x 1,800(H) mm or more.

#### Dimensions and Weight Unit: mm & kg

<b>e</b> nd hin ∝ hg					
	Width	Depth	Height	Weight	Remarks
SEM Column console	750	900	1,485	152	JEOL JAPAN
SEM Operation console	750	950	1,220	183	JEOL JAPAN
EDS + SemAfore PC Set	600	1800	740	40	OXFORD, JEOL
Cooling Water	350	380	900	20	EYELA JAPAN
Step down transformer JP.	320	400	680	65	220v to 100 volt.
Sputter Coater UK.	360	450	380	15	FISON UK.

## Installation Layout



Unit: mm

Note 1: Fig. 1 shows a typical installation layout for the JSM-5410LV Scanning Microscope with an optional as EDS (energy dispersive X-ray spectrometer)

Be sure to maintain service areas at the left and rear sides of the microscope even if only a small layout space is available.

Note 2: Install the microscope well apart from facilities producing vibrations or electromagnetic waves (such as roads, husky passages, railroads, elevators, air conditioners and their air outlets, transmission lines, etc.). Note 3: This microscope does not require any blackout curtain.

#### JEOL JSM-5410LV SEM & OXFORD EDS Customer ref.

- 1. STREC Chula Uni. ศูนย์เครื่องมือจุฬา
- 2. Faculty of Dentistry Chula Uni. ทันตแพทย์จุฬา
- 3. Maejo University เทคโนโลยีชีวภาพ ม.แม่โจ้
- 4. Faculty of Dentistry Mahidol Uni. ทันตแพทย์มหิดล
- 5. MTEC สวทช.
- 6. MPAD TISTR วว.
- 7. Ubon Uni. เทคโนโลยีชีวภาพ ม.อุบล
- 8. Kasetsart Uni. เทคโนโลยีชีวภาพ ม.เกษตร บางเขน
- 9. PCTT
- 10. NMB บ.มินิแบ
- 11. TDK
- 12. Faculty of Tropical Medicine, Mahidol Uni เวชศาสตร์ เบตร้อน มหิดล
- 13. Pramongkut hospital รพ.พระมงกุฎ
- 14. SCG ปูนซีเมนต์
- 15. Siam Steel Cord
- 16. Etc. และอื่นๆ

## More Info : www.dosem24hr.com

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## \*สภาพเครื่องสมบูรณ์พร้อมใช้งาน

\*\*ตรวจสอบสเป็คและทดสอบเครื่อง ณ. <u>www.dosem24hr.com</u> จริงได้ ก่อนตัดสินใจ